Wet-Burn-Wet Abatement Evaluation on 300mm Silicon Nitride Deposition

SESHA Conference 2017

Agenda Outline

- Introduction and Objectives
- Test Setup and Timeline
- Chamber Cleaning Test Results
- Deposition Process Test Results
- Discussion
- Questions

Introduction and Objectives

Silicon Nitride Deposition

• Silicon Nitride is typically used in semiconductors as a dielectric, oxidation mask or a passivation layer

```
3 \operatorname{SiH}_4 + 4 \operatorname{NH}_3 \rightarrow \operatorname{Si}_3\operatorname{N}_4 + 12 \operatorname{H}_2
```

- Process flows also include a carrier gas and possibly N2O
- As required, removal of deposits from tool reaction chamber walls requires a chamber cleaning step often through flows of NF3 and carrier gases

Burn-Wet Operation Summary

SiN – Dep Process Abatement



Output Si-Deposits Si-particles NH4F Sub-µ particles High NOx

Wet-Burn-Wet Operation Summary

SiN – Dep Process Abatement



Project Scope

- Evaluate an Airgard Encompass wet-burn-wet abatement unit for performance against currently installed TPU-4 burn-wet abatement unit
 - Remove ammonia prior to house exhaust system
 - Concerns regarding excess ammonium fluoride particulates
 - Concerns regarding excess NOx generated due to ammonia
- Further concerns regarding Greenhouse Gas Destruction
 - NF3 DRE
 - N2O DRE and effects on NOx
 - Performance with CDA and O₂
- Reliability and maintenance of unit

Test Setup and Timeline

Testing Method

- Extractive Fourier Transform Infrared (FTIR) Spectroscopy
- Procedures were consistent with EPA Protocol for Measuring Destruction or Removal Efficiency of Fluorinated Greenhouse Gas Abatement Equipment in Electronics Manufacturing (March 2010)
- Data was gathered using Method 2, "Total Volume Measurements", which measures DREs under actual process conditions where byproducts are formed and analytical determined influent/effluent exhaust flows were performed via process NF₃ or SF₆ tracer gas injection

Timeline for Encompass Testing (Day 1)



Timeline for TPU Testing (Day 2)

MFC NF₃ Metered Flows 1500 sccm, 1250 sccm, 1000 sccm, Plasma Off, for Influent Flow Determinations via FTIR



FTIR Influent/Effluent concentration measurements Chamber Clean "CDA Fire Mode" NF3, Carrier flows



Total Effluent Flow Determination MFC Metered Flows of SF6 tracer gas at three distinct flow setting per both O2 and CDA fire modes for dilution factor determination FTIR Influent/Effluent concentration measurements 24 wafer dep. steps "CDA Fire Mode" SiH4, NH3 flows

Average Influent/Effluent Flows and DFs

Encompass Avg. Influent Flow	43.0 slm		
TPU Avg. Influent Flow	44.5 slm		
Encompass Avg. Effluent Flow, O ₂ Fire	145 slm		
Encompass Avg. Effluent Flow, CDA Fire	410 slm		
TPU Avg. Effluent Flow, CDA Fire	419 slm		
Encompass O ₂ Fire DF	3.4		
Encompass CDA Fire DF	9.5		
TPU CDA Fire DF	9.4		

Chamber Clean Step Results

Chamber Clean Testing Objectives

- What is the effective DRE for NF3?
- Is there appreciable destruction of NF3 in "CDA fire" mode?

Certain fabs do not have available O2 supplies plumbed throughout the support level

To claim abatement, MRR requires fabs to test their abatement units

• Are there differences in levels of NOx generated between the abatement units?

TPU NF_3 DRE in "CDA Fire"

NF3in NF3out NF3DRE



Encompass NF₃ DRE in "O₂ Fire"



Encompass NF₃ DRE in "CDA Fire"

NF3in MF3out MF3DRE



NF3 DRE Results

• Both Encompass operating in "O2 fire" mode and TPU in "CDA fire" mode achieved average DREs of about 99%.

Extensive maintenance of the TPU was performed one day prior to testing including the combustor liner

Previous testing by TI on other TPUs at another TI facility indicates that DRE is greatly affected by combustor liner plugging

- The average DRE for the Encompass in "CDA fire" mode was ~80%
- EPA Subpart I default DRE for NF3 is 88% from Table I-16

TPU Chamber Clean with "O₂ Fire"



Encompass NF3 Chamber Clean with "CDA Fire"



Encompass NF₃ Chamber Clean with "O₂ Fire"



NOx Outlet Comparison Combined



Chamber Clean NO_x Results

 The Encompass abatement unit running in "CDA fire" mode was very comparable to the TPU also in "CDA fire" mode

	Avg. NO (ppmv)	Avg. NO ₂ (ppmv)	Avg. N ₂ O (ppmv)
Encompass @ CDA Fire	645	169	152
TPU (CDA Fire)	787	163	236

- The two also have similar dilution factors
- The NOx concentration was markedly higher for the Encompass unit running in "O2 fire" mode
 - This is expected as higher temperatures will favor NO2 production
 - Interestingly, due to the lower total flow rate, the mass flow of NOx is actually less than the CDA fire modes



Mass Flow Rate of NOx

Data Point

Process Step Results

Process Step Testing Objectives

- What is the NH3 Removal Efficiency?
- Does the Encompass wet-burn-wet first stage remove the NH3 effectively and what are the differences in NOx production?

TPU Silicon Nitride Deposition Process with "CDA Fire"



Encompass Silicon Nitride Deposition Process with "CDA Fire"





Encompass CDA Versus TPU CDA NO_x Out (Process Emissions)

Process Step NO_x Results

 Again, the Encompass abatement unit running in "CDA fire" mode was very comparable to the TPU also in "CDA fire" mode. The inlet concentrations of NH3 were pretty much identical.

	Avg. NO (ppmv)	Avg. NO ₂ (ppmv)	Avg. N ₂ O (ppmv)
Encompass @ CDA Fire	34	8	< 10
TPU (CDA Fire)	212	31	251

 Appears that the first stage wet scrubber which allows removal of excess NH3 prior to the burn chamber, makes a significant difference in NOx and N2O production. It is believed that excess NH can react with NO to produce N2O.

$$NH + NO \leftrightarrow N2O + H$$

Encompass Silicon Nitride Deposition Process with Undercoat and "O₂ Fire"



Process Step NO_x Results (cont.)

- The Encompass running in "O2 fire" mode data seems to back up the efficacy of the first stage wet-scrubber as the N2O levels drop below detect after the pre-coat step.
- The N2O destruction efficiency of the Encompass in "O2 fire" mode also averaged ~99% although we do see increases in NOx production in the effluent as expected.
- It is also evident that the N2O/NOx levels did not fluctuate with NH3 input as seen in the TPU.

Miscellaneous Discussion

Utility and Maintenance

- Utilities forecasted for the Encompass were comparable to that of the existing Edwards TPU
- Final cost analysis showed an increase of about 20% from forecasted costs, mainly due to water usage. However the costs of operation of the Encompass unit was still comparable to the TPU.
- The Encompass unit, once the testing was done, ran for ~13 months without maintenance needed. Repairs were needed after the unit developed a water leak. This ability to run without maintenance reduces the cost of operation of the Encompass significantly versus the TPU. Estimates show overall a difference of ~60% savings.
- Although particulates were not quantified, it was noticed that the Encompass effluent seemed to have a higher concentration of aerosol particulates than the TPU. It is theorized that the particulates may have been trapped by the ceramic liner used by the TPU. This is partially evident in the Encompass' ability to run continuously without need for maintenance.

NOx and DRE Discussion

- It is important to take into account that NOx production is a complex issue and that the burners in both the Encompass and TPU unit were not tuned to minimize NOx prior to testing.
- In developing the Mandatory Reporting Rule Subpart I, EPA concluded that maintenance performed on an abatement unit could affect the DRE for greenhouse gases. Lowering the frequency of maintenance can give greater confidence that a unit is achieving the require DREs. Also, internal testing at TI has shown that TPU DRE degrades over time as chamber liner plugs up during normal processing.
- Also, as buildup in the combustion chamber is minimal (due to the Encompass Wetted Wall technology), maintenance is not expected to have any effect on DRE.

Future Evaluation Considerations

- Next step could potentially be to measure DREs again to track possible degradation over time of NF3
- Results from the wet-burn-wet technology seems promising in removing unwanted chemistries from reaching the combustion chamber. TI plans to evaluate a unit for tungsten oxide deposition